## **Supporting info**

	Cu(CHDA)	Cu <sub>3</sub> (BTC) <sub>2</sub>	Cu(INA) <sub>2</sub>
Time (Sec.)	15	180	60
Voltage (V)	30	2.5	2.5
Frequency (Hz)	0.5	0	0
Solvent (ml) EtOH : H <sub>2</sub> O	75 : 25	50 : 50	50 : 50

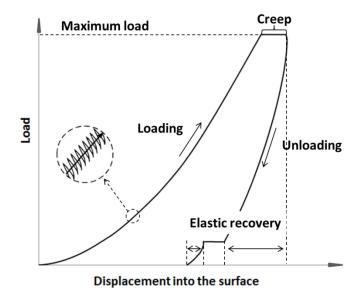
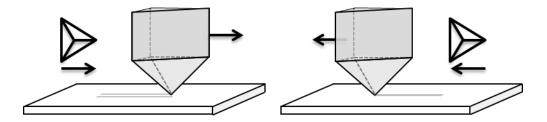


Figure S1. A typical load-displacement curve. On the unloading curve, the horizontal segment at 90% unload corresponds to thermal drift measurement.



**Figure S2** The scratch movements depending on the geometry of the indenter, with either the sharp tip (left, denoted as  $0^{\circ}$ ) or blunt side (right, at 180°) facing in the scratching direction.

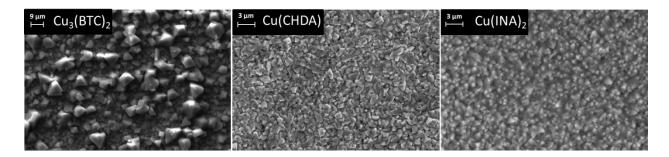


Figure S3 Details of the electrochemical growth of Cu<sub>3</sub>(BTC)<sub>2</sub>, Cu(CHDA) and Cu(INA)<sub>2</sub> on copper anodes.

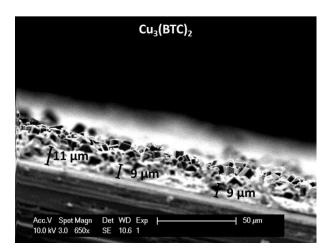


Figure S4 Cross-section SEM of the  $Cu_3(BTC)_2$  coating on a copper anode, with a thickness of 9-11  $\mu m$ 

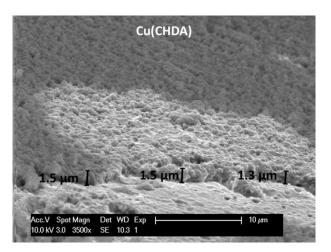


Figure S5 Cross-section SEM of the Cu(CHDA) coating on a copper anode, with a thickness of 1.3-1.5  $\mu$ m.

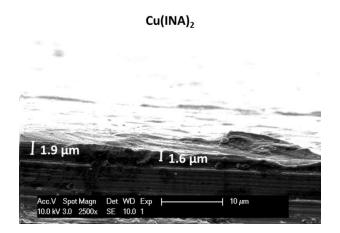


Figure S6 Cross-section SEM of the Cu(INA)<sub>2</sub> coating on a copper anode, with a thickness of 1.6-1.9 µm.

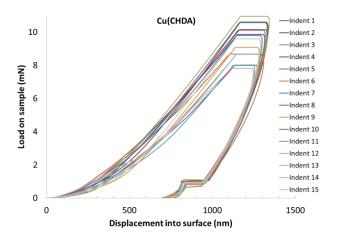


Figure S7 Load-displacement curves of 15 indents on Cu(CHDA).

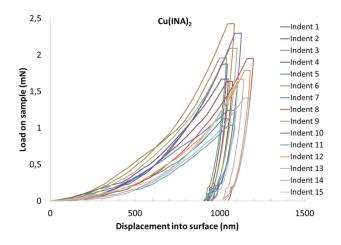


Figure S8 Load-displacement curves of 15 indents on Cu(INA)<sub>2</sub>.

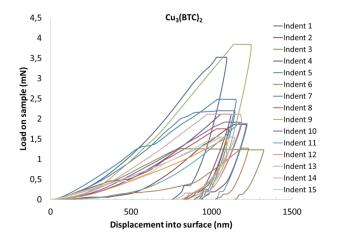


Figure S9 Load-displacement curves of 15 indents on Cu<sub>3</sub>(BTC)<sub>2</sub>.

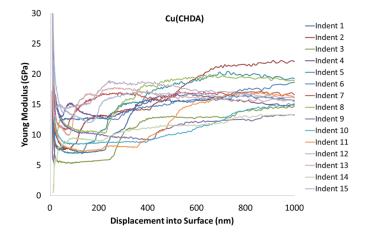


Figure S10 Young's moduli as a function of indentation depth for 15 indents on Cu(CHDA).

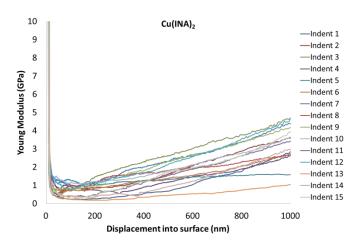


Figure S11 Young's moduli as a function of indentation depth for 15 indents on Cu(INA)<sub>2</sub>.

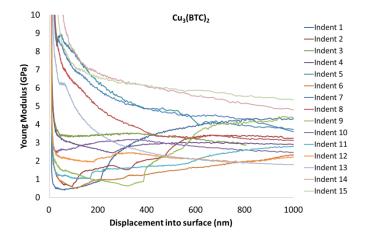


Figure S12 Young's moduli as a function of indentation depth for 15 indents on Cu<sub>3</sub>(BTC)<sub>2</sub>.

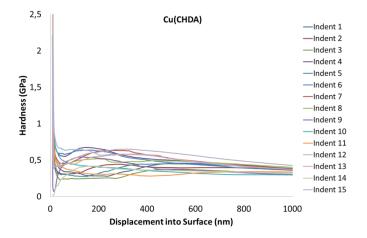
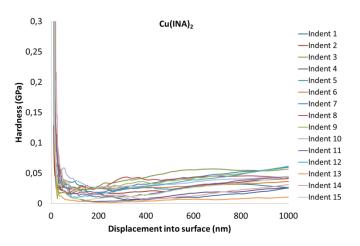


Figure S13 Hardness as a function of indentation depth for 15 indents on Cu(CHDA).





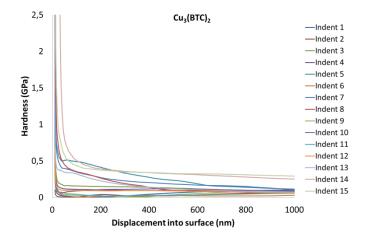


Figure S15 Hardness as a function of indentation depth for 15 indents on Cu<sub>3</sub>(BTC)<sub>2</sub>.

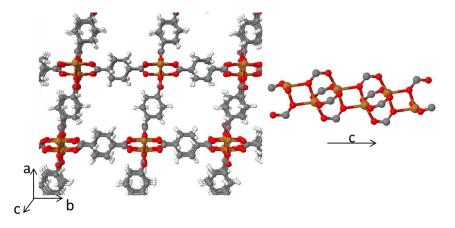


Figure S16 The structure of Cu(*trans*-1,4-cyclohexanedicarboxylate) with the 1D pores (left), the inorganic Cu-oxo-chain forming the rigid pillar of the structure in the *c*-direction (right).

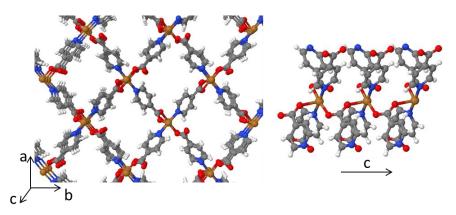


Figure S17 The structure of Cu(isonicotinate)<sub>2</sub> with the 1D pores (left), square pyramidal copper atoms coordinated by two pyridyl groups and two carboxylate groups of four isonicotinate units in a monodentate fashion at the equatorial positions, together with one carboxylate of an isonicotinate in apical position (right).

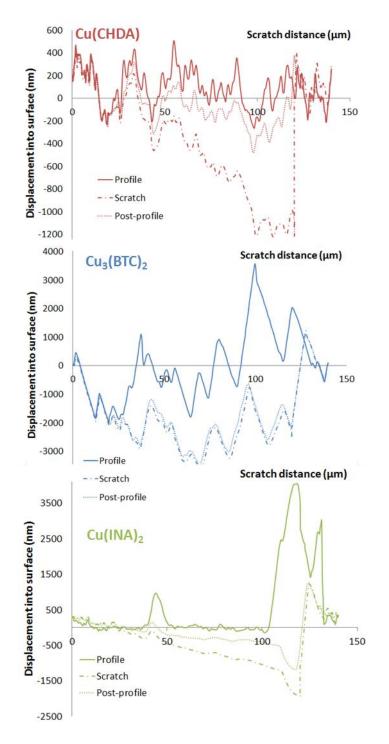


Figure S18. Scratch profiles in the push mode with the displacement into the surface as a function of scratch distance. The load was set at 0 mN at  $20\mu m$  and linearly increased up to 10 mN at  $120 \mu m$ 

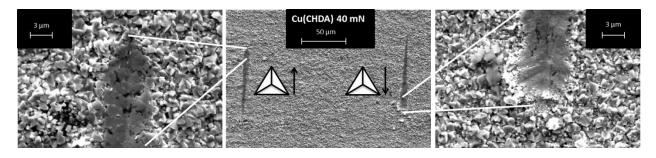


Figure S19. Scratch profiles of Cu(CHDA) with a maximum load of 40mN; the side panels show details of the residual scratch.

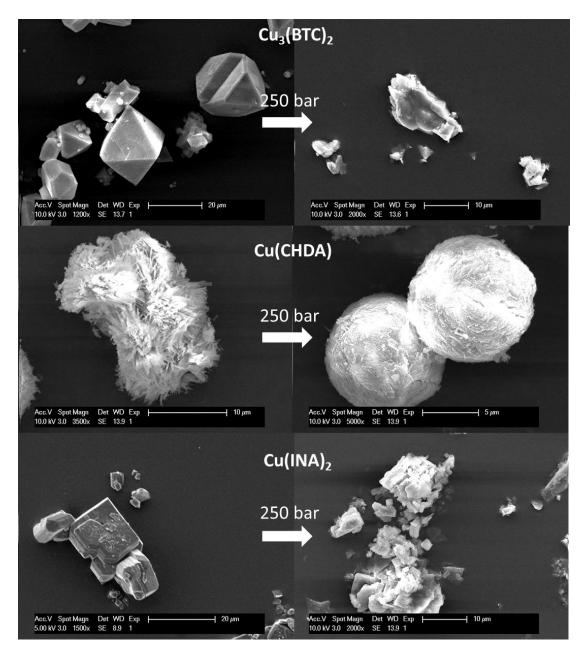


Figure S20. SEM pictures of solvothermally synthesised Cu<sub>3</sub>(BTC)<sub>2</sub>, Cu(CHDA) and Cu(INA)<sub>2</sub>; before and after 250 bar uniaxial pressure.

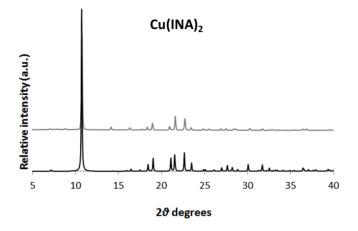


Figure S21. Thin film XRD pattern of Cu(INA)<sub>2</sub> collected from a film grown on a pure copper electrode (top) and reference XRD pattern (bottom).

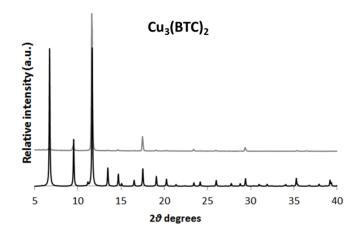


Figure S22. Thin film XRD pattern of Cu<sub>3</sub>(BTC)<sub>2</sub> collected from a film grown on a pure copper electrode (top) and reference XRD pattern (bottom).

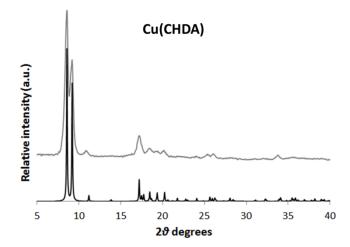


Figure S23. Thin film XRD pattern of Cu(CHDA) collected from a film grown on a pure copper electrode (top) and reference XRD pattern (bottom).

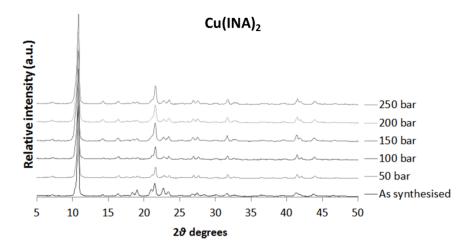


Figure S24. XRD patterns of Cu(INA)<sub>2</sub> powders before (as synthesised) and after certain applied pressures (X bar).

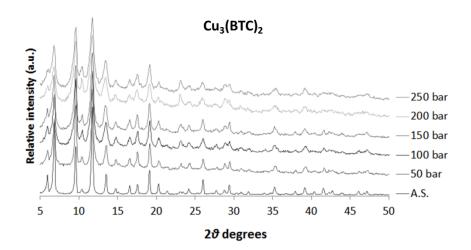


Figure S25. XRD patterns of Cu<sub>3</sub>(BTC)<sub>2</sub> powders before (as synthesised) and after certain applied pressures (X bar).

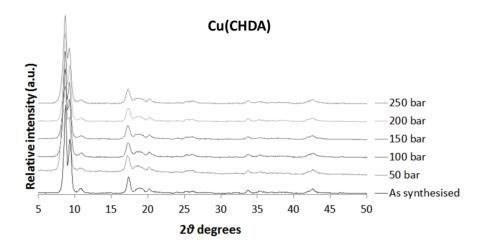


Figure S26. XRD patterns of Cu(CHDA) powders before (as synthesised) and after certain applied pressures ( X bar).